

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



Applicant : Kuo-Huang Hsieh

Serial No. : 10/674,153

: Art Unit #1762

Filed : 29 September 2003

: Examiner: J. Lin

Title : MICRO-STAMPING METHOD FOR
PHOTOELECTRIC PROCESS

RESPONSE TO RESTRICTION REQUIREMENT
AND AMENDMENT

Mail Stop NO FEE
Honorable Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

/ Applicant, by the undersigned attorney hereby responds to the outstanding
Official Action dated 11 September 2006 which is a Restriction Requirement.
Please amend the above-referenced patent application as follows:

Amendments to the Claims begin on page 2 of this paper.

Remarks/Arguments begin on page 15 of this paper.